WE CLAIM:

- 1. A surface emitting laser, comprising:
- a plurality of spaced apart mirrors;
- a light amplifying region between said mirrors;
- a substrate; and
- a photon transparent ohmic contact for passing light energy therethrough whereby light emission through said surface emitting laser may be monitored.
- 2. The laser as set forth in claim 1, wherein said photon transparent ohmic contact is positioned on said substrate.
- 3. The laser as set forth in claim 1, wherein said photon transparent ohmic contact is positioned on an epitaxial side of said laser.
- 4. The laser as set forth in claim 1, wherein said surface emitting laser is a top emitting vertical cavity surface emitting laser.
- 5. The laser as set forth/in claim 1, wherein said surface emitting laser is a bottom emitting vertical cavity surface emitting laser.
- 6. The laser as set forth in claim 1, wherein said transparent ohmic contact comprises a contact devoid of apertures.
- 7. The laser as set forth in claim 1, wherein said ohmic contact has a thickness between 1 nanometer and 100 nanometers.
- 8. The laser as set forth in claim 1, wherein said ohmic contact comprises indium tin oxide.
- 9. The laser as set forth in claim 1, wherein said mirrors have equivalent reflectivity.
- 10.// The laser as set forth in claim 1, wherein said mirrors have reversed reflectivity.

- 11. A method for monitoring light emission from a surface emitting laser, said laser including:
 - a plurality of spaced apart mirrors;
 - a light amplifying region between said mirrors;
 - a substrate;
 - a photon transparent ohmic contact;
 - contacting said laser with a source of energy to generate light; and monitoring emitted light transmitted through said transparent ohmic contact.
- 12. The method as set forth in claim 11, wherein said laser is a bottom emitting vertical cavity surface emitting laser.
- 13. The method as set forth in claim 12, further including the step of providing mirrors with equivalent reflectivity.
- 14. The method as set forth in claim 12, wherein said ohmic contact comprises indium tin oxide.
- 15. The method as set forth in claim 11, further including the step of providing mirrors with reversed reflectivity.
- 16. The method as set forth in claim 11, wherein said photon transparent contact is positioned on said substrate.
- 17. The method as set forth in claim 11, wherein said photon transparent contact is positioned on an epitaxial side of a bottom emitting vertical cavity surface emitting laser.

